

Nano Transistors Performance Analysis

Shafiq Uddin

Uttara University, Dhaka, Bangladesh

ABSTRACT

Nanowire Transistors have attractive attention due to the feasible high performance and excellent controllability of device current. In this paper, the performance analysis of nanowire transistors made of different materials such as Silicon (Si), Germanium (Ge), Gallium Arsenide (GaAs) and Indium Arsenide (InAs) are investigated. Self-consistent 3D simulations are used due to their 3D distribution of electron density and electrostatic potential. The output characteristics of the nanowire transistors are studied in details for all the materials of different transport orientation. Nanowire, a 3D Poisson self-consistent simulator is used for simulation which can study the 3D transport in nanowire transistor considering phonon scattering based on the effective-mass approximation.

Keywords: Nanowire Transistor, NEGF, Coupled Mode Space, Uncoupled Mode Space, Crystal Orientation.

1. INTRODUCTION

Nanowires are attracting much interest from those seeking to apply nanotechnology and especially those investigating nanoscience. Nanowire transistors are an emerging class of materials with great potential for applications in future electronic devices. Although conventional planar Metal Oxide Semiconductor Field Effect Transistor (MOSFETs) are approaching nanometer scale, but their performance becomes limited by short channel effects, increasing OFF-state current and poor electrostatic control of the channel [1]. Unlike other low-dimensional systems, nanowires have two quantum- confined directions but one unconfined direction available for electrical conduction. This allows nanowires to be used in applications where electrical conduction, rather than tunneling transport is required. Because of their unique density of electronic states in the limit of small diameters, nanowires are expected to exhibit significantly different optical, electrical and magnetic properties to their bulk 3D crystalline counterparts.

Nanowires are nanoscale structures which are frequently single crystal materials and are typically cylindrical in shape. They can be formed in a variety of materials including metallic (e.g., Ni, Pt, Au), semiconducting (e.g., Si, Ge, GaAs, InAs, InP, GaN, etc.), and insulating (e.g., SiO₂, TiO₂), but are most frequently fabricated using semiconducting materials. They have fascinated attention not only because of their extremely small size, but also their size causes new physics (quantum effects) to apply. This does not occur classically which can cause changes in material properties [2]. Three phenomena that are the most notable are: (i) as the diameter of nanowire decreases, the energy band gap can change, (ii) the diameter of nanowire can change the material's character [3], and (iii) ballistic transport, i.e. without scattering, can occur which can lead to notably improved device performance

The reason which leads the researchers think about replacement of planar MOSFET is Nanowire Transistor (NWT) that has the strongest gate control over planar MOSFET and other proposed structures. However, at this time the NWT is still in its early stage, there is a lot of space to optimize the structure parameters and lots of new phenomenon to be explored by both experimental and computational approach, for instance, we need to determine the optimal diameter, the best material and the effect of random dopant or surface roughness or phonon scattering on its performance. Figure 1 shows a schematic structure of a nanowire transistor showing metal source and drain electrodes with the nanowire.

In this research, the output characteristics are studied by different transport orientation (i.e., 100, 110 and 111) and varying the oxide thickness in details for the NWT formed of four different semiconducting materials like Silicon (Si), Germanium (Ge), Gallium Arsenide (GaAs) and Indium Arsenide (InAs).

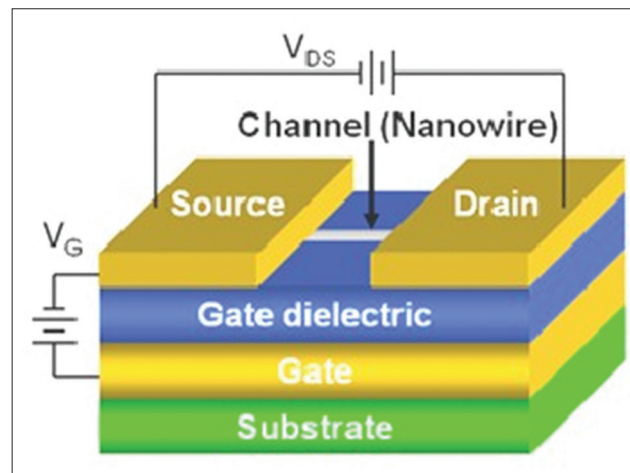


Figure 1: Schematic of a Nanowire Transistor showing metal source and drain electrodes with the Nanowire

2. HOMOGENEOUS NANOWIRE BASED DEVICES

In the case of nanowires with homogeneous structure and composition, Silicon Nanowires (Si NWs) have most extensively been studied [4]. This is due partly to the dominance of Si in the semiconductor industry, but also reflects the high-level of control of structure and doping demonstrated in fundamental Si NW growth studies [4-5]. Additionally, other nanowire materials such as Ge, GaAs, InAs, GaN, and metal oxides have also received broad attention [6-9].

A. Silicon Nanowires (Si NWs)

Researches on nanowires began to accelerate in 1998, when Si NWs with diameters < 20 nm and lengths > 1 μ m were demonstrated using a laser-ablation method [10]. The ability to prepare nanowires with diameters < 20 nm made it possible for the first time to produce devices that could approach a 1D limit desirable for high-performance transistors. Initial efforts led to demonstration of NWTs and basic devices configured using crossed nanowire geometry, including p-n diodes and bipolar transistors [11]. However, the electrical properties of nanowires in these initial studies were far from optimal, for example leading to low apparent carrier mobilities and large sample to sample variations. These studies thus underscored the significance of growth of nanowires with controlled material and electrical properties.

B. Germanium Nanowires (Ge NWs)

Ge NW devices have also been studied by several groups [6], [12] & [13] due to the higher electron and hole mobilities compared with Si. Compared to Si NW, Ge NW devices are expected to have smaller contact effects because the smaller Ge bandgap will yield a lower Schottky barrier at the metal/NW interface. For example, studies of p-type Ge NW devices with Pd S/D contacts yielded a hole mobility of 600 $\text{cm}^2/\text{V}\cdot\text{s}$ [14]. In addition, complementary n-type and p-type Ge NW devices were demonstrated based on a surface doping approach to prevent uncontrolled sidewall deposition during the nanowire growth [12]. Prototype gate-all-around devices were also demonstrated by Zhang et al. [13] using atomic-layer deposition and magnetron sputtering to uniformly coat an Al_2O_3 dielectric layer and an Al gate layer. Compared with the back-gated Ge NW devices, the gate-all-around devices showed excellent subthreshold performance due to the improved electrostatics. The ON-state performance of these latter devices was lower than earlier studies due to the series resistance caused by the finite positive (albeit small) Schottky barriers.

C. Gallium Arsenide Nanowires (GaAs NWs)

To push that past limit, researchers are working on transistor designs that rely on materials with better electrical properties than silicon. Now researchers have made high-performance transistors from a promising candidate material: GaAs nanowires. GaAs materials have higher charge mobility than Si, which should allow III/V transistors to switch ON and OFF faster than silicon-based devices but the challenge is cost. GaAs wafers are much more expensive and far smaller than silicon wafers, meaning manufacturers wouldn't be able to make as many chips at once as they do with Si to keep chip costs down. NWs offer a way around the wafer problem, because they should use less material. The growth of the wires is catalyzed by spots of gold, patterned in a tight line by electron-beam lithography onto a surface. As the chamber fills with gaseous precursors, the gold spots

catalyze the deposition of solid GaAs. By controlling the ratio of gallium and arsenide, and conditions such as temperature and pressure, it is shown that the gold catalyst moves along the surface as the nanowire grows, rather than leaving the surface and forming the nanowires vertically. Then nanowire arrays to make a type of high-performance transistors similar to those found in radar equipment and cell-phones. Each 10- μ m-wide transistor contains about 30 nanowires, along with three electrodes. A top electrode called a gate applies a voltage across the device to switch the nanowires between conducting, or "ON" and insulating, or "OFF" states. In the ON state, charges flow between source and drain electrodes. The transistors have blistering switching speeds, turning ON and OFF 75 billion times a second, or at 75 GHz. The previous record for planar nanowire transistors was 1.8 GHz. Researchers are also thinking that mobility of InAs is three times higher than GaAs, so if it is possible to make and if it works, then we will get THz speeds.

D. Indium Arsenide Nanowires (InAs NWs)

InAs nanowires have widely been studied as a building block for n-type FETs [14-16]. InAs is an attractive material for numerous reasons. First, its small effective electron mass (0.023 m_0) results in high electron-mobility in bulk materials. Second, an electron gas layer is known to form at the surface of planar InAs due to Fermi level pinning in the conduction band. Third, the formation of an electron gas combined with the small bandgap of 0.35 eV should relatively yield transparent contacts to InAs nanowire devices. Studies of InAs NWTs have yielded depletion-mode n-channel FETs with electron mobilities on the order 3000 cm²/V \cdot s [14-15]. The epitaxial growth of InAs nanowires have led to the demonstration of vertical nanowire structures with a wrap-around gate with a low saturation voltage of 0.15 V [16]. In addition, the clean electron conduction channel has led to the demonstration of quantum devices including single-electron transistors and quantum dots in Chemical Beam Epitaxy (CBE) grown InAs/InP nanowire axial hetero structures in which the InP layers serve as tunnel barriers [15].

3. METHODOLOGY

To deeply understand device physics of NWTs and to assess their ultimate performance limits, simulation work is necessary and important. In contrast to a planar MOSFET, which has a uniform charge and potential profile in the transverse direction (normal to both the gate and the source-to-drain direction), an NWT has a 3D distribution of electron density and electrostatic potential. As a result, a 3D simulator is required for the simulation of NWTs.

In this paper, a 3D self-consistent quantum simulation of NWTs based on the effective-mass approximation (whose validity in then a scale device simulation has been established in Ref. [20]) is proposed. The methodology of this work is shown as flowchart in Figure 2. The calculation involves solution of a self-consistent 3D Poisson equation for the electrostatic potential. After that, the calculation involves solution of a 2D Schrödinger equation with open boundary conditions for each cross section of the nanowire transistor to obtain the electron sub bands (along the nanowire) and Eigen functions. The 2D Schrödinger by a (coupled/uncoupled) mode space approach is solved which provides both computational efficiency and high accuracy as compared with direct real space calculations. Coupled/Uncoupled Non Equilibrium Green Function (NEGF) transport equations is solved for the electron charge density. Phonon-electron interaction calculation is done with the self-consistent Born approximation. First step is repeated to calculate the electrostatic potential. If the self-consistent loop has converged, the electron current is calculated using the NEGF approach.

Different transport models are implemented into simulator. In this paper, both ballistic NEGF model and dissipative NEGF model is discussed. Ballistic NEGF model gives the upper performance limit of Si, Ge, GaAs and InAs NWTs, and a dissipative NEGF model with a simple treatment of scattering with the Buttiker probes offers an efficient way to capture scattering in the quantum mechanical frame work.

A. Coupled Mode Space Approach

In this part of the work, the Coupled Mode Space (CMS) approach is briefly discussed and listed out the basic equations for the particular case of interest. In the 3D domain, the full stationary Schrödinger equation is given by -

$$H_{3D} \psi(x,y,z) = E \psi(x,y,z) \quad (1)$$

Where, H_{3D} is the 3D device Hamiltonian. Assuming an ellipsoidal parabolic energy band with a diagonal effective-mass tensor (for the case that the effective-mass tensor includes non-zero off diagonal elements), H_{3D} is defined as -

$$H_{3D} = \frac{\hbar^2}{2} \left(\frac{\partial^2}{\partial x^2} + \frac{\partial^2}{\partial y^2} + \frac{\partial^2}{\partial z^2} \right) + U(x, y, z) \quad (2)$$

Here, m_x^* , m_y^* and m_z^* are the electron effective mass in the x, y, and z directions, respectively; $U(x, y, z)$ is the electron conduction band-edge profile in the active device. After the device Hamiltonian H is obtained, the electron density and current can be calculated using the NEGF approach. The NEGF approach is a commonly used method for the simulation of nanoscale electronic devices. The retarded Green's function of the active device is defined as -

$$G(E) = [E - H - \Sigma_S(E) - \Sigma_1(E) - \Sigma_2(E)]^{-1} \quad (3)$$

Here, Σ_S is the self-energy that accounts for the scattering inside the device (zero in the case of ballistic approach), and Σ_1 (Σ_2) is the self-energy caused by coupling between device and the source (drain) [20].

B. Uncoupled Mode Space Approach

The uncoupled mode space approach gives quantum confinement and transport separately. In the simulation of NWTs, it is assumed that the shape of the Si body is uniform along the x direction. As a result, the confinement potential profile (in the yz plane) varies very slowly along the channel direction.

For instance, the conduction band-edge $U(x, y, z)$ takes the same shape but different values at different x. For this reason, the eigen functions $\xi_m(y, z; x)$ are approximately the same along the channel although the Eigen values $E_{sub m}(x)$ is different. So it is assumed,

$$\xi_m(y, z; x) = \xi_m(y, z) \quad (4)$$

The retarded Green's function for mode m of the active device is rewritten as [20]

$$G_m(E) = [E - E_{sub m} - \Sigma_m(E) - \Sigma_m(E) - \Sigma_m(E)]^{-1} \dots \dots \dots 2 \quad (5)$$

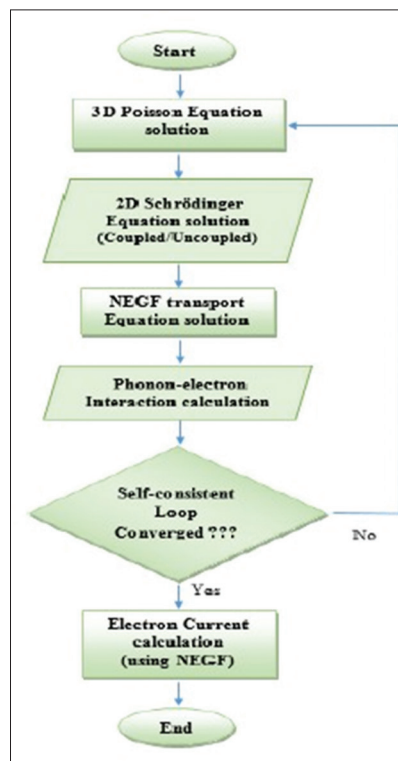


Figure 2: Methodology of this work.

C. NEGF Formalism

The simulation of electronic devices generally contains self-consistent solution of the electrostatic potential and carrier distribution inside the device. Over the years, device engineers have improved our collective knowledge of carrier transport and semiconductor physics. Earlier treatment of electrons and holes as semi-classical particles with an effective mass was good enough to predict semiconductor device behavior and the drift-diffusion equation was adequate to describe carrier transport.

MOSFETs have shrunk to nanoscale dimensions, which have required a re-examination of this approach to device modeling. A more sophisticated analysis of the device physics is needed, such as the Non Equilibrium Green's Function (NEGF) approach, to model devices all the way to ballistic level (< 10 nm) [1][19]. The NEGF transport model is by far the most rigorous method among existing quantum transport models and is the approach utilized in this modeling study.

4. SIMULATION RESULTS AND DISCUSSION

In this work, 3D "Nanowire" simulator is used for the simulation of NWTs. The simulation software used for the modeling of nanowire transistors is based on the work done by Hong-Hyun Park et al. and his colleagues at Purdue University [17-18].

A. Simulation

Because of longer simulation time, the uncoupled mode space NEGF transport is considered only. Although Si is the most common and economical material used in semiconductor industry, it has some limitations and maybe reaches its physical end soon. There are some other materials which are very active in research and exhibit some promising improvement over Si. Hence, the Si with other semiconductors for the nanowire transistor channel material is compared. The gate work function of 4.15 eV is used, which is for the metal Aluminium (Al). The nanowire diameter is considered to be 4 nm, oxide thickness of SiO_2 is 1 nm, gate length is of 8 nm and the source-drain extension length is of 8 nm each. The doping profile of 2×10^{20} per cm^3 is considered for the source-drain extensions. The channel region doping is set to zero which provides results similar to that of an intrinsic channel.

The gate voltage is kept fixed at 400 mV and the drain current is extracted for different drain bias by using Si as the channel material with uncoupled mode space approach. The same thing is repeated by using Ge, GaAs and InAs as the channel material.

Figure 3 represents Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with Uncoupled mode space approach for 100 crystal orientations. Here the nanowire transistor Ge, GaAs and InAs as channel material has more ON current when compared with that of the Si counterpart for crystal orientation "100" with uncoupled mode transport.

Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with Uncoupled mode space approach for crystal orientations "110" is shown in Figure 4.

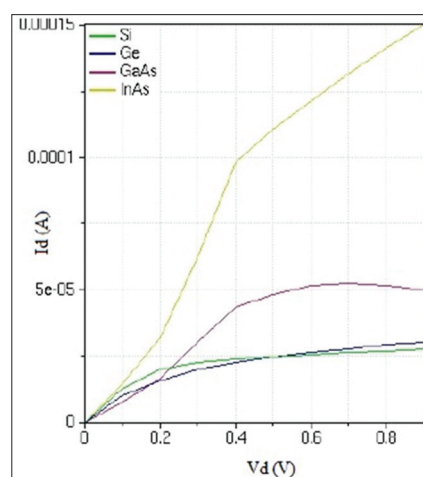


Figure 3: Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with uncoupled mode space approach for 100 crystal orientations

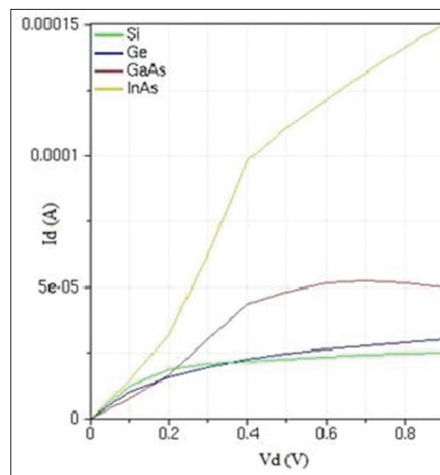


Figure 4: Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with Uncoupled mode space approach for 110 crystal orientations.

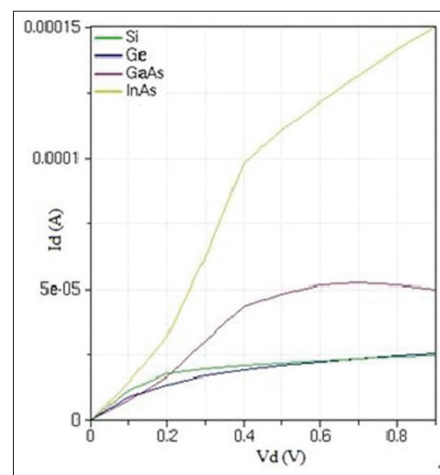


Figure 5: Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with Uncoupled mode space approach for 111 crystal orientations

Figure 5 also represents Drain Current (I_d) vs. Drain Voltage (V_d) plot of nanowire transistor for four different materials (Si, Ge, GaAs, and InAs) with Uncoupled mode space approach but different crystal orientations “111”.

It is inferred from the above Figure 3, 4 and 5 that the nanowire transistor Ge, GaAs and InAs as channel material has more ON current when compared with that of the Si counterpart for various crystal orientations (100, 110 and 111) with uncoupled mode transport. From the analysis of the different material’s NWTs, the orientation of 110 has less ON current compared with orientation of (100 and 111) for Si material. Ge, GaAs and InAs has almost same ON current in all the crystal orientations.

4. CONCLUSION

In this paper, the performance analysis of nanowire transistors made of different materials such as Si, Ge, GaAs and InAs are investigated. The output characteristics of the nanowire transistors are studied in details for all the materials of different transport orientations i.e.- 100, 110 and 111. Si has less ON current in crystal orientation 110, but comparatively more ON current in crystal orientation 100 and 111. Ge, GaAs and InAs all have more ON current than conventional Si in all the crystal orientations and almost same ON current in all the orientations. InAs has the highest ON current in all the crystal orientations. For different orientation of mode space approach, Ge, GaAs and InAs NWTs give better performance than conventional Si NWTs. So, conclusion can be drawn that Ge, GaAs and InAs have NWTs have higher mobility than Si NWTs and InAs has the highest mobility.

REFERENCES

- Y. Taur and T. H. Ning, "Fundamentals of Modern VLSI Devices," Cambridge Press, New York, p. 268, 1998.
- T. Kamins, "Beyond CMOS Electronics: Self-Assembled Nanostructures," The Electrochemical Society (ECS) Interface, p.46-49, Spring 2005.
- M. S. Dresselhaus, Y. M. Lin, O. Rabin, A. Jorio, A. G. Souza Filho, M.A. Pimenta, R. Saito, Ge. G. Samaonidze, and G. Dresselhaus, "Nanowires and Nanotubes," Materials Science & Engineering C (Biomimetic and Supramolecular Systems), vol. 23 (1-2), p. 129-140, 2003.
- Y. Cui, Z. H. Zhong, D. L. Wang, W. U. Wang, and C. M. Lieber, "High performance silicon nanowire field effect transistors," Nano Lett., vol.3, no. 2, pp. 149–152, Jan. 2003.
- G. F. Zheng, W. Lu, S. Jin, and C. M. Lieber, "Synthesis and fabrication of high-performance n-type silicon nanowire transistors," Adv. Mater., vol. 16, no. 21, pp. 1890–1893, Sep. 2004.
- D.W.Wang, Q.Wang, A. Javey, R. T u, H. J. Dai, H. Kim, P. C.McIntyre, T . Krishnamohan, and K. C. Saraswat, " Germanium nanowire field effect transistors with SiO₂ and high- κ HfO₂ gate dielectrics," App Phys.Lett., vol. 83, no. 12, pp. 2432–2434, Sep. 2003.
- X. Jiang, Q. Xiong, S. Nam, F. Qian, Y. Li, and C. M. Lieber, " InAs/InP radial nanowire heterostructures as high electron mobility devices," Nano Lett., vol. 7, no. 10, pp. 3214–3218, Sep. 2007.
- Y. Li, J. Xiang, F. Qian, S. Gradecak, Y. Wu, H. Yan, D. A. Blom, and C. M. Lieber, "Dopant-free GaN/AlN/AlGaIn radial nanowire heterostructures as high electron mobility transistors," Nano Lett., vol.6, no. 7, pp. 1468–1473, Jul. 2006.
- F. Qian, Y. Li, S. Gradecak, D. L.Wang, C. J. Barrelet, and C.M. Lieber, "Gallium nitride-based nanowire radial heterostructures for nanophotonics," Nano Lett., vol. 4, no. 10, pp. 1975–1979, Sep. 2004.
- A. M. Morales and C. M. Lieber, " A laser ablation method for the synthesis of crystalline semiconductor nanowires," Science, vol.279, no. 5348, pp. 208–211, Jan. 1998.
- Y. Huang, X. F. Duan, Y. Cui, L. J. Lauhon, K. H. Kim, and C. M.Lieber, "Logic gates and computation from assembled nanowire buildingblocks," Science, vol. 294, no. 5545, pp. 1313–1317, Nov. 2001.
- A. B. Greytak, L. J. Lauhon, M. S. Gudiksen, and C. M. Lieber, " Growth and transport properties of complementary germanium nanowire field effect transistors," Appl. Phys. Lett., vol. 84, no.21, pp.4176–4178, May 2004.
- L. Zhang, R. T u, and H. Dai, " Parallel core-shell metal–dielectric– semiconductor germanium nanowires for high-current surround-gate field-effect transistors," Nano Lett., vol. 6, no. 12, pp. 2785–2789, Oct. 2006.
- S. A. Dayeh, D. P. R. Aplin, X. T . Zhou, P. K. L. Yu, E. T . Yu, and D.L. Wang, "High electron mobility InAs nanowire field-effect transistors," Small , vol. 3, no. 2, pp. 326–332, 2007.
- C. T helander, M. T . Bjork, M. W. Larsson, A. E. Hansen, L. R. Wallenberg, and L. Samuelson, " Electron transport in InAsnanowires and heterostructure nanowire devices," Solid State Commun., vol. 131, no. 9/10, pp. 573–579, Sep. 2004.
- T . Bryllert, L. E. Wernersson, L. E. Froberg, and L. Samuelson, "Vertical high-mobility wrap-gated InAs nanowire transistor," IEEE Electron Device Lett., vol. 27, no. 5, pp. 323–325, May 2006.
- Hong-Hyun Park and Gerhard Klimeck, " Quantum approach to electronic noise calculations in the presence of electron -phonon interactions" Physical Review B 82(4), pages 125328, 2010.
- Hong-Hyun Park, Seonghoon Jin, Young June Park, and Hong Shick Min, "Quantum simulation of noise in silicon nanowire transistors with electron-phonon interactions," Journal of Applied Physics 105(4), pages 023712, 2009.
- M. P. Anantram, M. Lundstrom and D. Nikonov, " Modeling of Nanoscale Devices," Proc. IEEE, v. 96, p. 1511-1550, 2008.
- Jing Wang, Eric Polizzi, Mark Lundstrom, " A three-dimensional quantum simulation of silicon nanowire transistors with the effective- mass approximation," Journal of Applied Physics 96(4), pages 2192- 2203, 2004.